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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/045,895	10/29/2001	Stephen Keetai Park	2000.029996/TT3586C	3826
23720	7590 08:28:2003			
	S, MORGAN & AME	EXAMINER		
HOUSTON.	IMOND, SUITE 1100 . TX - 77042		LEE, HSIEN MING	
			ART UNIT	PAPER NUMBER

DATE MAILED: 08/28/2003

Please find below and/or attached an Office communication concerning this application or proceeding.

			r				
		Application No.	Applicant(s)				
Office Action Summary		10/045,895	PARK, STEPHEN KEETAI				
		Examiner	Art Unit				
		Hsien-Ming Lee	2823				
Perio	The MAILING DATE of this communication od for Reply	appears on the cover sheet w	vith the correspondence address				
	SHORTENED STATUTORY PERIOD FOR REI HE MAILING DATE OF THIS COMMUNICATIO Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. If the period for reply specified above is less than thirty (30) days, a If NO period for reply is specified above, the maximum statutory per Failure to reply within the set or extended period for reply will, by sta Any reply received by the Office later than three months after the meanned patent term adjustment. See 37 CFR 1.704(b).	N. t.1.136(a). In no event, however, may a reply within the statutory minimum of thiod will apply and will expire SIX (6) MO stute, cause the application to become A	reply be timely filed rly (30) days will be considered timely. NTHS from the mailing date of this communication. BBANDONED (35 U.S.C. § 133).				
1	Responsive to communication(s) filed on €	06 June 2003 .					
2a)□ This action is FINAL . 2b)⊠	This action is non-final.					
) Since this application is in condition for all closed in accordance with the practice uncosition of Claims						
) Claim(s) 1-20,41 and 42 is/are pending in t	the application.					
4a) Of the above claim(s) is/are withdrawn from consideration.							
5	5) Claim(s) is/are allowed.						
	6)⊠ Claim(s) 1-20,41 and 42 is/are rejected.						
7	Claim(s) is/are objected to.						
	Claim(s) are subject to restriction an	d/or election requirement.					
Appl	ication Papers						
9)☐ The specification is objected to by the Exam	iner.					
10)☐ The drawing(s) filed on is/are: a)☐ ad	ccepted or b) objected to by	the Examiner.				
	Applicant may not request that any objection to						
11) \square The proposed drawing correction filed on $_$	is: a)□ approved b)□	disapproved by the Examiner.				
	If approved, corrected drawings are required in	reply to this Office action.					
12)☐ The oath or declaration is objected to by the	Examiner.					
Prio	rity under 35 U.S.C. §§ 119 and 120						
13) Acknowledgment is made of a claim for fore	eign priority under 35 U.S.C.	§ 119(a)-(d) or (f).				
	a) ☐ All b) ☐ Some * c) ☐ None of:						
	 Certified copies of the priority docum 	ents have been received.					
	2. Certified copies of the priority docum	ents have been received in	Application No				
	Copies of the certified copies of the papplication from the International See the attached detailed Office action for a	Bureau (PCT Rule 17.2(a)).					
14	☐ Acknowledgment is made of a claim for dome	·					
ĺ	a) The translation of the foreign language Acknowledgment is made of a claim for dom	provisional application has I	peen received.				
	nment(s)	F,					
1) 🔯	Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449) Paper Not	5) Notice of	r Summary (PTO-413) Paper No(s) f Informal Patent Application (PTO-152)				

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DETAILED ACTION

- 1. The objection to specification, claims 6, 11 and 16, 112-second-paragraph rejection to claims 1 and 7 and double patenting rejection, as set forth in the previous Office action, are withdrawn.
- 2. Claims 1-20, 41 and 42 are pending in the application.

Claim Objections

Claim 1 is objected to because of the following informalities: in-consistent term.
 At line 15, "above the structure" should be – above the structure layer --.

Double Patenting

4. The nonstatutory double patenting rejection is based on a judicially created doctrine grounded in public policy (a policy reflected in the statute) so as to prevent the unjustified or improper timewise extension of the "right to exclude" granted by a patent and to prevent possible harassment by multiple assignees. See *In re Goodman*, 11 F.3d 1046, 29 USPQ2d 2010 (Fed. Cir. 1993); *In re Longi*, 759 F.2d 887, 225 USPQ 645 (Fed. Cir. 1985); *In re Van Ornum*, 686 F.2d 937, 214 USPQ 761 (CCPA 1982); *In re Vogel*, 422 F.2d 438, 164 USPQ 619 (CCPA 1970); and, *In re Thorington*, 418 F.2d 528, 163 USPQ 644 (CCPA 1969).

A timely filed terminal disclaimer in compliance with 37 CFR 1.321(c) may be used to overcome an actual or provisional rejection based on a nonstatutory double patenting ground provided the conflicting application or patent is shown to be commonly owned with this application. See 37 CFR 1.130(b).

Effective January 1, 1994, a registered attorney or agent of record may sign a terminal disclaimer. A terminal disclaimer signed by the assignee must fully comply with 37 CFR 3.73(b).

5. Claims 1-20, 41 and 42 rejected under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 21-24 of U.S. Patent No. 6,303,486.

Although the conflicting claims are not identical, they are <u>not patentably distinct</u> from each other because of the reasons as follow.

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The following list is a comparison regarding limitations between the instant invention and the Patent:

the instant invention

- forming a first sacrificial dielectric layer
 above a structure layer and adjacent a contact;
- forming a second sacrificial dielectric layer above the first sacrificial dielectric layer and the contact;
- forming an opening in the second sacrificial dielectric layer, wherein at least a portion of the opening is above at least a portion of the contact;
- forming a copper layer above the second sacrificial dielectric layer and in the opening;
- forming the copper interconnect by removing portions of the copper layer above the second sacrificial dielectric layer, leaving the copper interconnect in the opening;

the Patent

forming a first dielectric layer
above a structure layer;
forming a sacrificial dielectric layer
above the first dielectric layer
and above the copper via;
forming a second opening in the
sacrificial dielectric layer above
at least a portion of the copper
via;

forming a copper line in the second opening, the copper line contacting the at least the portion of the copper via;

planarizing a second dielectric layer (claim 23); wherein the second dielectric layer is formed above the first dielectric layer and adjacent to the copper line (claim 22);

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 removing the first and second sacrificial dielectric layers;

- forming a low dielectric constant
 dielectric layer above the structure
 and adjacent the copper interconnect
 and the contact; and
- 8. forming and patterning a mask layer above the low dielectric constant dielectric layer to have a mask layer opening above at least a portion of the copper interconnect (claim 4).

removing the sacrificial dielectric layer above the first dielectric layer (claim 21), i.e. inherently removing the sacrificial dielectric layer and the second dielectric layer;

forming a second dielectric layer, a

low dielectric constant material, adjacent to the copper line (claims 22 and 23); and forming and patterning a mask layer above the second dielectric layer to have a mask layer opening above at least a portion of the second copper structure (claim 24).

From the above comparison, it would have been obvious that a first dielectric layer of the Patent is equivalent to a first sacrificial dielectric layer of the instant invention; that a first sacrificial dielectric layer of the Patent is equivalent to a second sacrificial dielectric layer of the instant invention; that a copper via of the Patent is equivalent to a contact of the instant invention and that the low dielectric constant layer of the instant invention is equivalent to the second

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dielectric layer of the Patent. In addition, the features as shown in Figs. 15-16 of the Patent are equivalent to that of Figs. 5-6 of the instant invention.

Therefore, it would have been obvious to one of the ordinary skill in the art, at the time the invention was made, to recognize that both instant invention and the Patent claim a common subject matter, regardless the obvious variations, i.e. using different terms for describing same subject matters.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hsien-Ming Lee whose telephone number is 703-305-7341. The examiner can normally be reached on M-F (9:00 \sim 5:00).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 703-306-2794. The fax phone number for the organization where this application or proceeding is assigned is (703) 305-3431.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

Hsien-Ming Lee Examiner

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August 19, 2003